

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Application Number: 10/685,550  
Attorney Docket Number: SENS.005US1  
Filing Date: October 14, 2003  
Applicants: Wayne G. Renken  
Application Title: PROCESS CONDITION SENSING WAFER AND DATA  
ANALYSIS SYSTEM  
Examiner: Samir M. Shah  
Art Unit: 2856

**COMMENTS ON STATEMENT OF REASONS FOR ALLOWANCE**

The Applicants object to the Examiner's reasons for allowance, to the extent, if any, that the Examiner's reasons for allowance based on this reference or any of the other cited references may be interpreted as introducing limitations not recited in the claims. The Examiner's comments regarding criticality of any particular component of the claimed invention or characterization of the cited references reflect merely the view of the Examiner and should not be interpreted as narrowing the scope of the claim. The scope of the present invention should be determined with reference to the paramount rule of claim construction that claims are given their plain meaning, in the broadest manner possible along with their full scope of equivalents (unless otherwise specified by definitions provided by the Applicants).

Respectfully submitted,  
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